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35.C13974

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)
TADAHIRO OHMI, ET AL.) : Examiner: Not Yet Assigned
Application No.: 09/425,015) : Group Art Unit: 2874
Filed: October 25, 1999) :
For: GAS SUPPLY PATH)
STRUCTURE, GAS SUPPLY :
METHOD, LASER OSCILLATING)
APPARATUS, EXPOSURE :
APPARATUS, AND DEVICE)
PRODUCTION METHOD : February 17, 2000

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FFR ?? 2000

TECHNOLOGY CENTER 2800

Assistant Commissioner for Patents
Washington, D.C. 20231

INFORMATION DISCLOSURE STATEMENT

Sir:

In compliance with the duty of disclosure under 37 C.F.R. § 1.56 and in accordance with the practice under 37 C.F.R. §§ 1.97 and 1.98, the Examiner's attention is directed to the document listed on the enclosed Form PTO-1449. A copy of the listed document is also enclosed.

The concise explanation of relevance for the non-English document, Japanese Patent Laid-Open Application No. 8-83945 may be found in the accompanying English abstracts describing an excimer laser oscillator.

CONCLUSION

It is respectfully requested that the above information be considered by the Examiner and that a copy of the enclosed Form PTO-1449 be returned indicating that such information has been considered.

Applicants' undersigned attorney may be reached in our New York office by telephone at (212) 218-2100. All correspondence should continue to be directed to our address given below.

Respectfully submitted,

Dawn A. Bauer
Attorney for Applicants
Registration No. 29,767

FITZPATRICK, CELLA, HARPER & SCINTO
30 Rockefeller Plaza
New York, New York 10112-3801
Facsimile: (212) 218-2200